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Nagata

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(54) **REACTOR TUBE FOR SEMICONDUCTOR PRODUCTION DEVICES**

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(73) Assignee: **Tokyo Electron Limited**, Tokyo (JP)

(**) Term: **15 Years**

(21) Appl. No.: **29/578,225**

(22) Filed: **Sep. 20, 2016**

(30) **Foreign Application Priority Data**

Mar. 30, 2016 (JP) 2016-006969

(51) **LOC (10) Cl.** **13-03**
(52) **U.S. Cl.**
USPC **D13/182**
(58) **Field of Classification Search**
USPC D13/158–177, 179, 180, 182, 199, 122, D13/144; D10/104.1, 108, 61, 62; D11/143, 144, 152; D14/216, 240, 356, D14/509, 210; D17/22; D23/323, 328, D23/333, 335, 336, 337, 341, 352, 357, D23/370, 385, 386, 399, 400, 499, 331, D23/406; D12/303, 315; 118/50, 722, 118/715, 724, 733; 205/118, 123; D9/500, 452, 454; D15/122, 199, 138; D8/16, 19, 323, 399, 45; D16/135, 219, D16/302; D7/367, 404, 503, 523, 584, D7/586, 624.1, 630, 340, 677; D26/24, D26/36, 110; D19/40; D25/100; D6/332
CPC C25D 17/001; C25D 17/08; C25D 17/10; C25D 7/10; C25D 7/12; H01L 21/283; H01L 21/285; H01H 9/02; H01H 9/0214; H01H 13/04; H01H 21/08; H01S 5/02204; C01B 13/0281; Y10S 148/06
See application file for complete search history.

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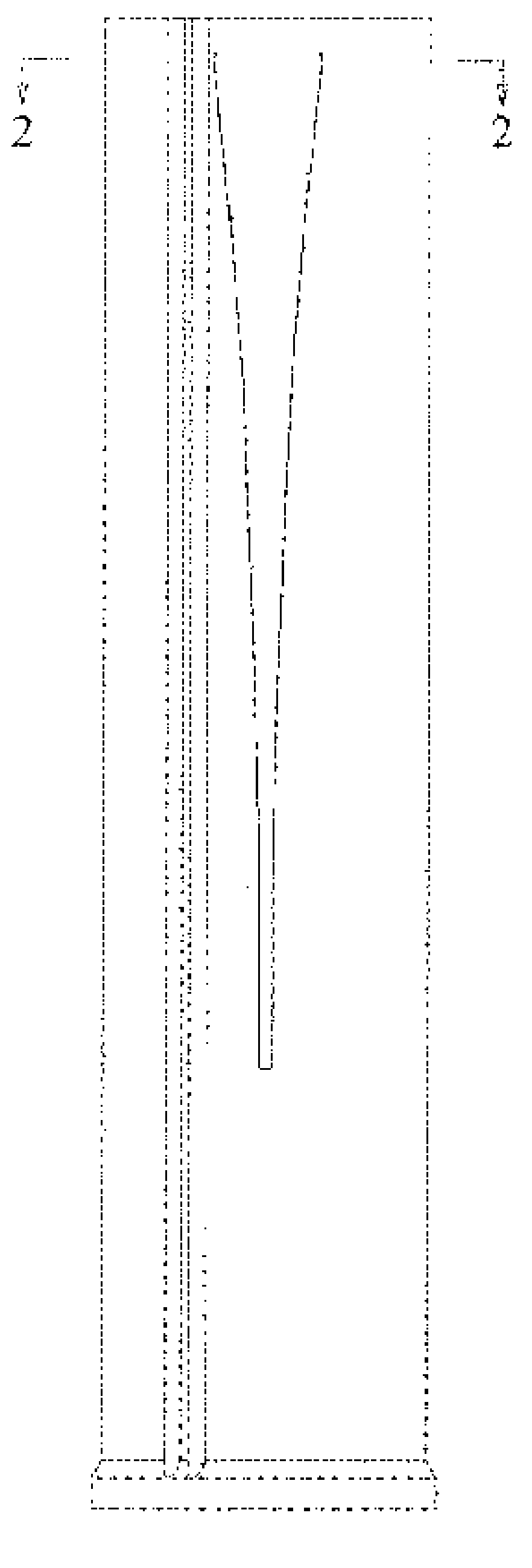
(57) **CLAIM**

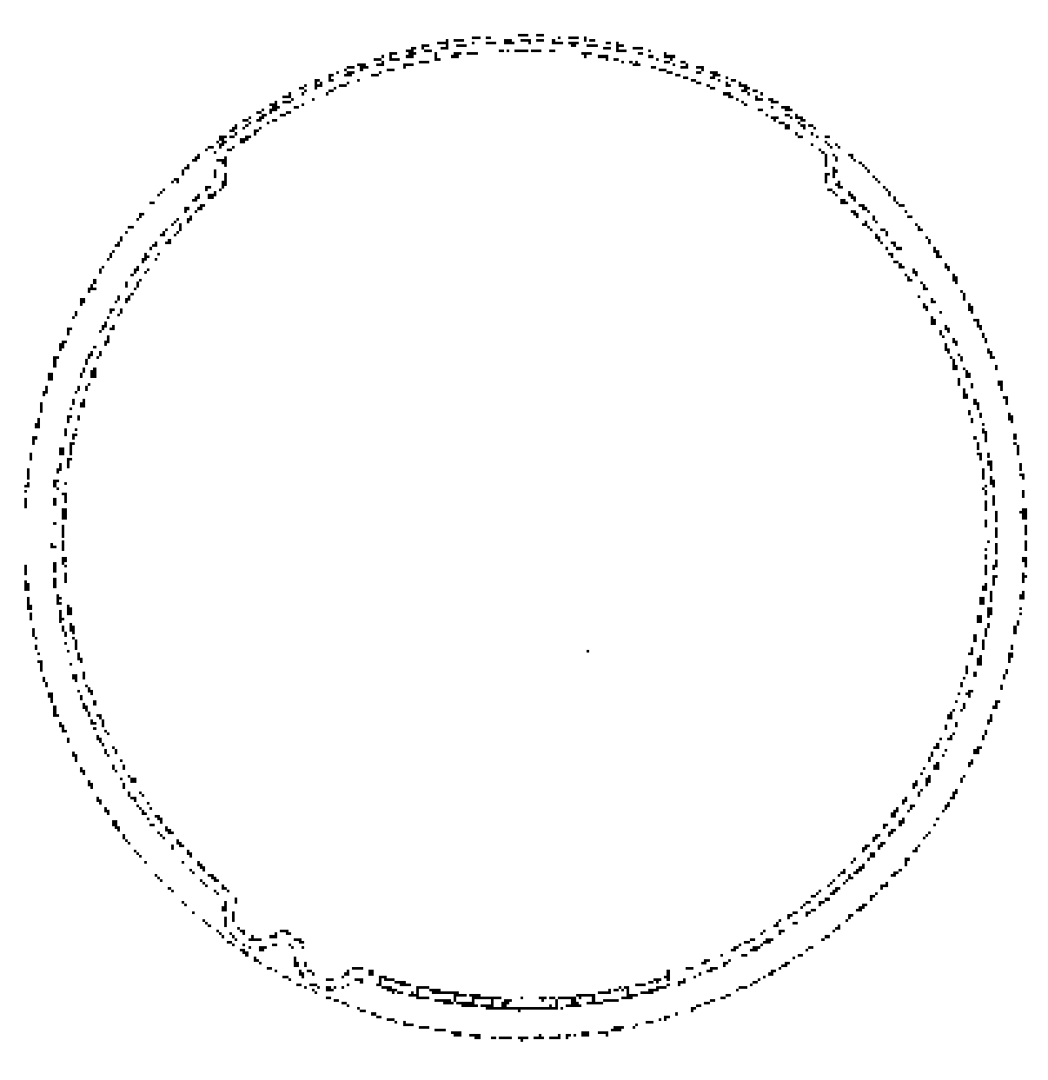
The ornamental design for a reactor tube for semiconductor production devices, as shown and described.

DESCRIPTION

FIG. **1** is a front view of a reactor tube for semiconductor production devices, showing our new design;
FIG. **2** is an enlarged cross-sectional view, along line **2-2** in FIG. **1**;
FIG. **3** is a top plan view thereof;
FIG. **4** is a bottom plan view thereof;
FIG. **5** is a right side view thereof;
FIG. **6** is a left side view thereof; and,
FIG. **7** is a cross-sectional view, along line **7-7** in FIG. **6**, shown with additional environment related to use being shown in broken lines.
The broken lines shown in the drawings represent portions of the reactor tube for semiconductor production devices that form no part of the claimed design. The rear view of the reactor tube for semiconductor production devices has been omitted because it does not illustrate the claimed design.

1 Claim, 5 Drawing Sheets





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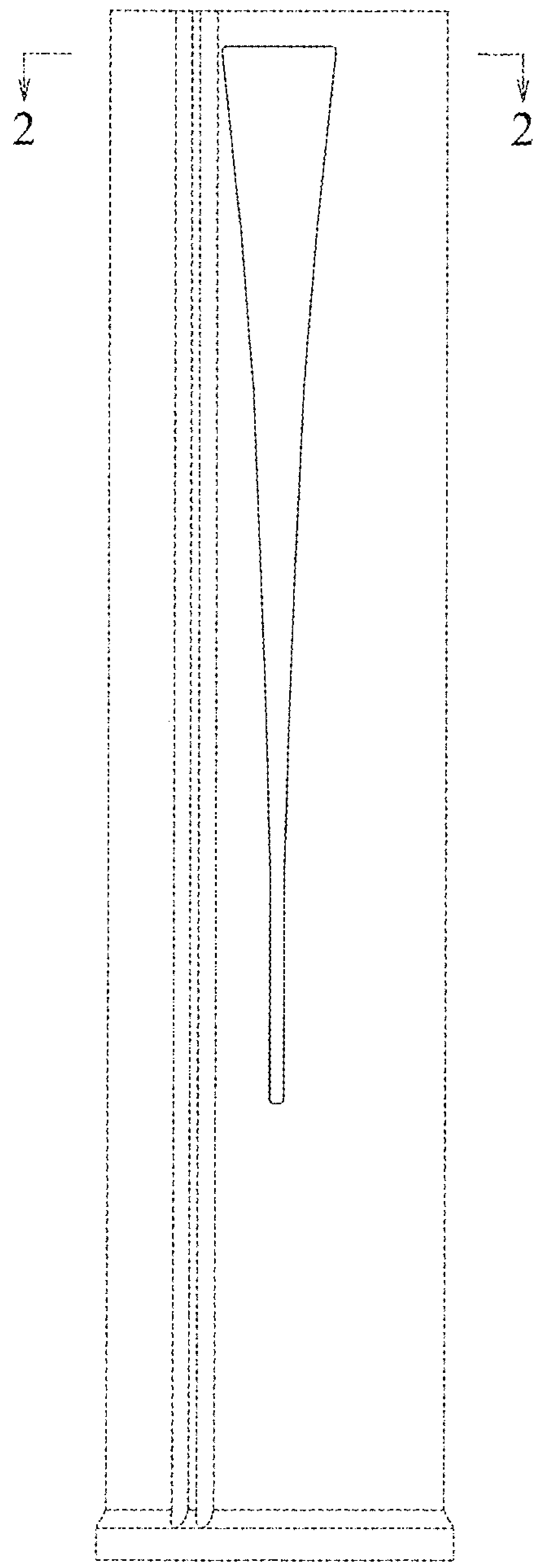

Fig.1

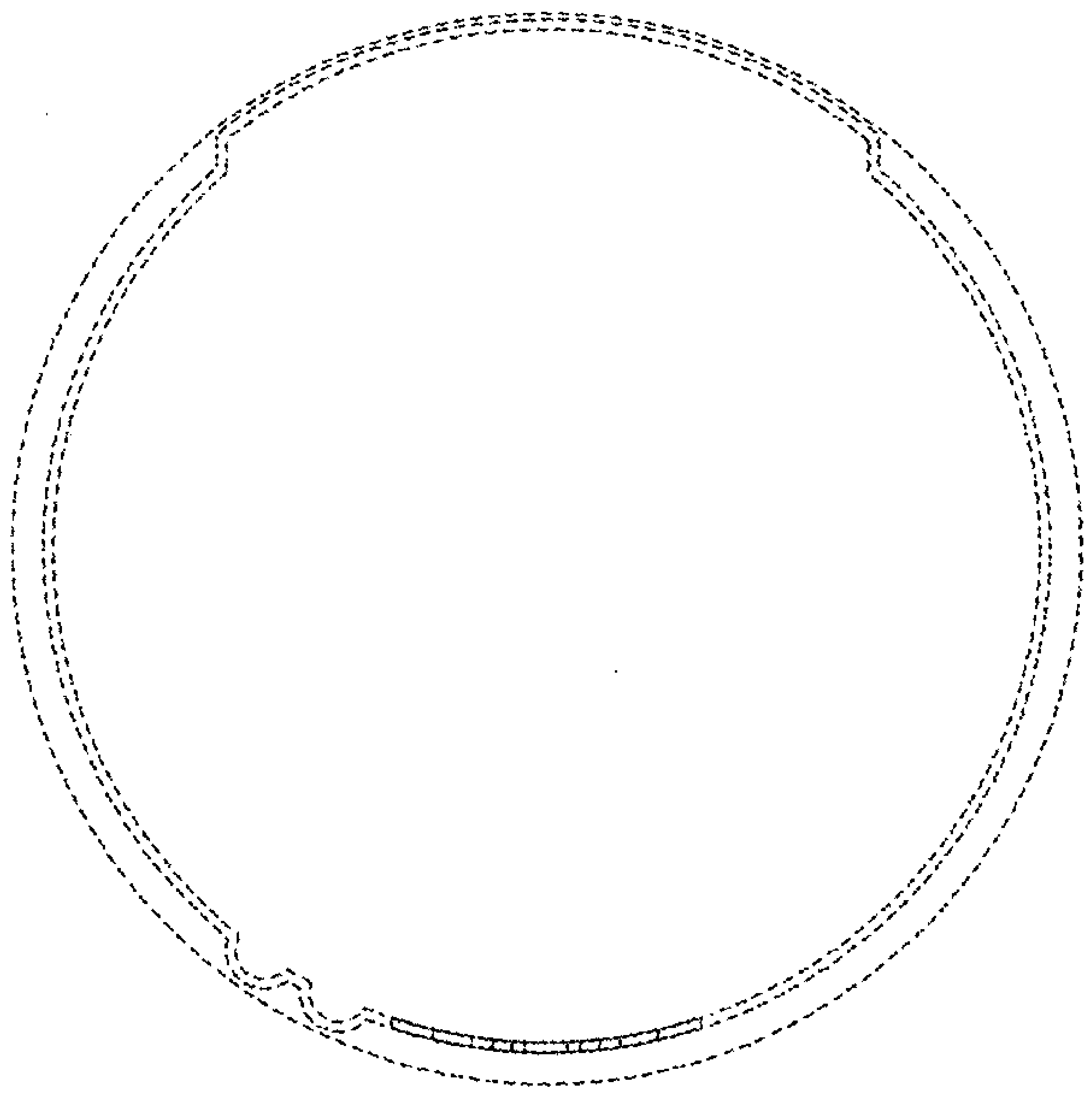

Fig.2

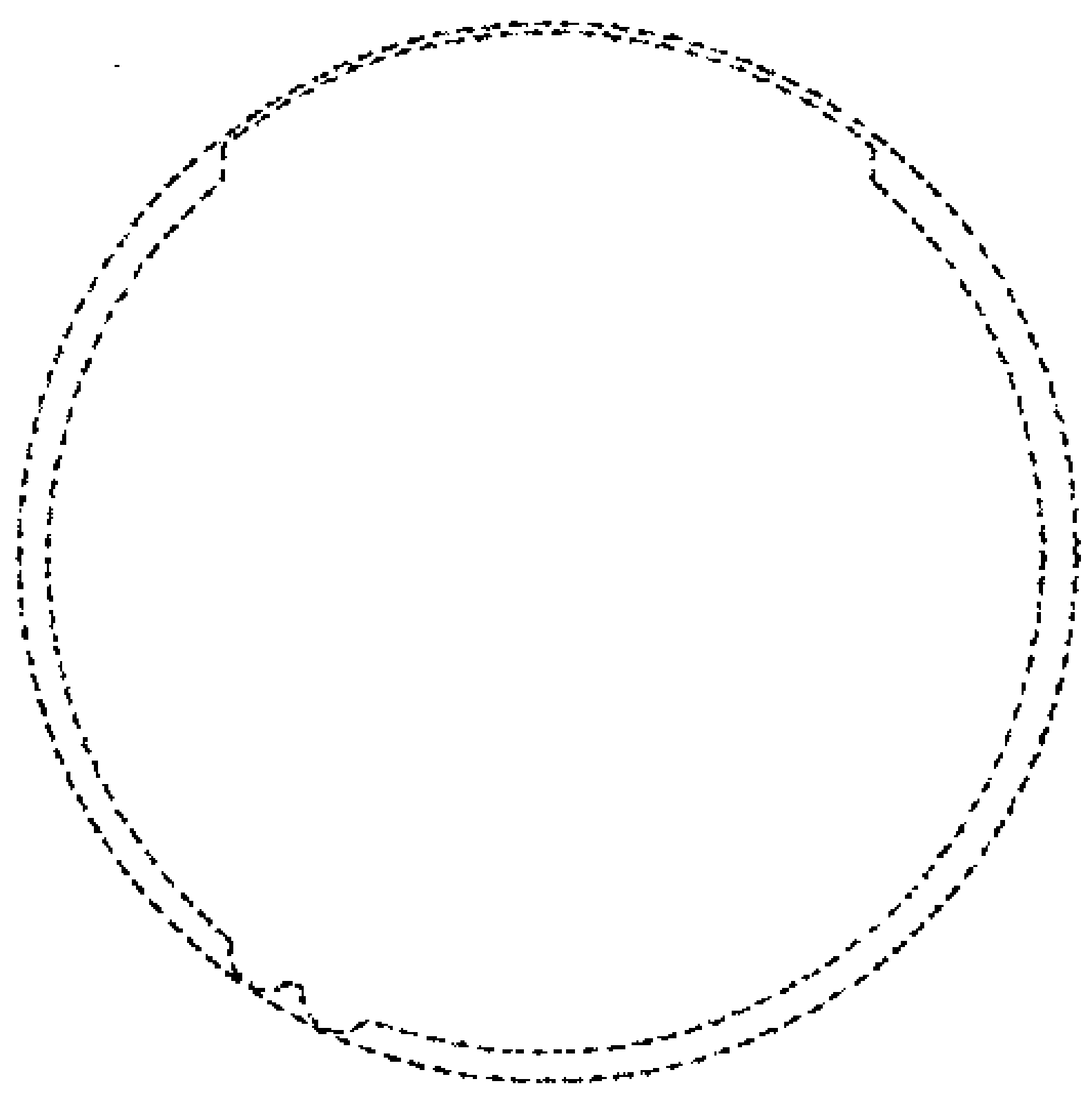

Fig.3

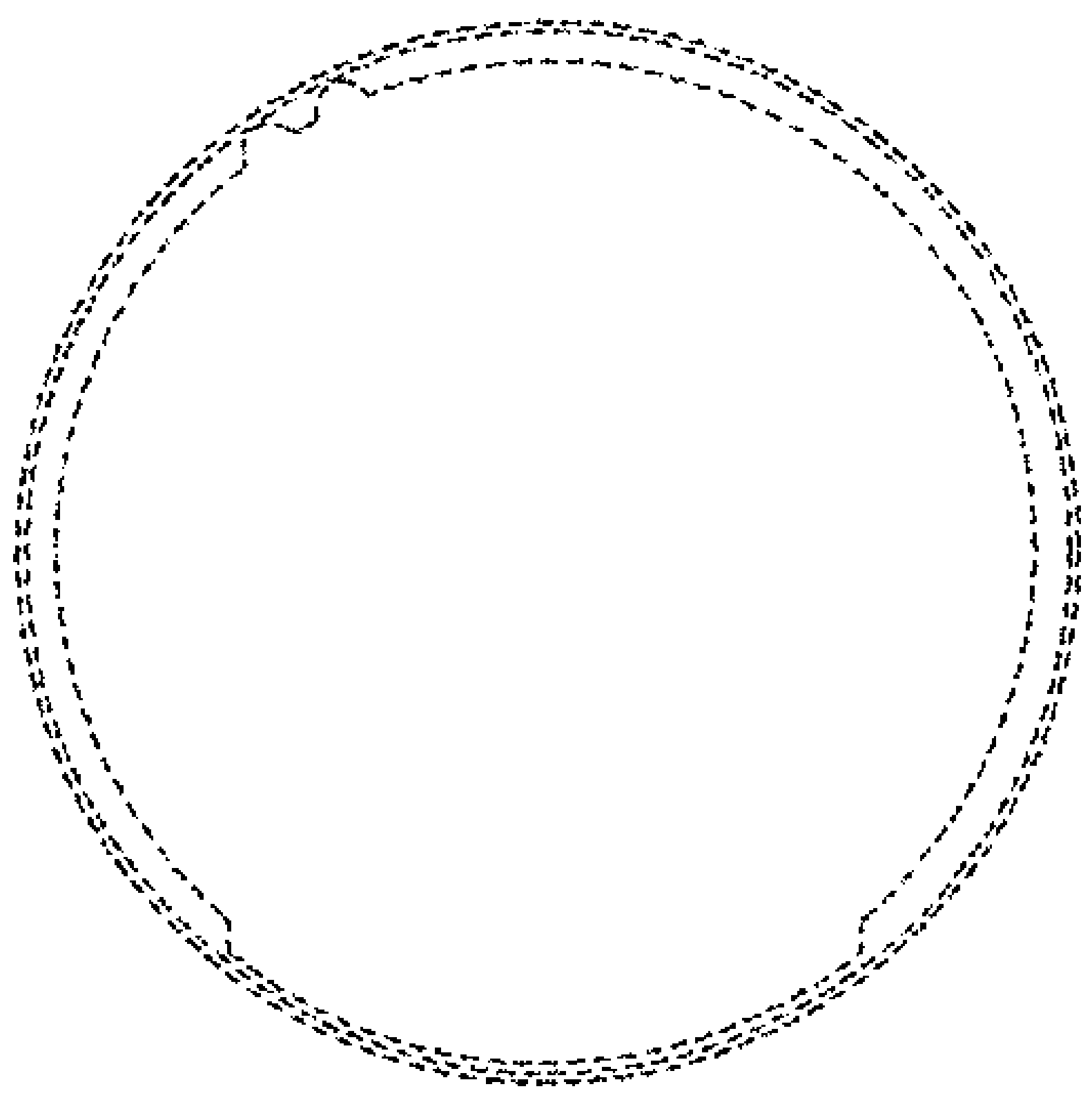

Fig.4

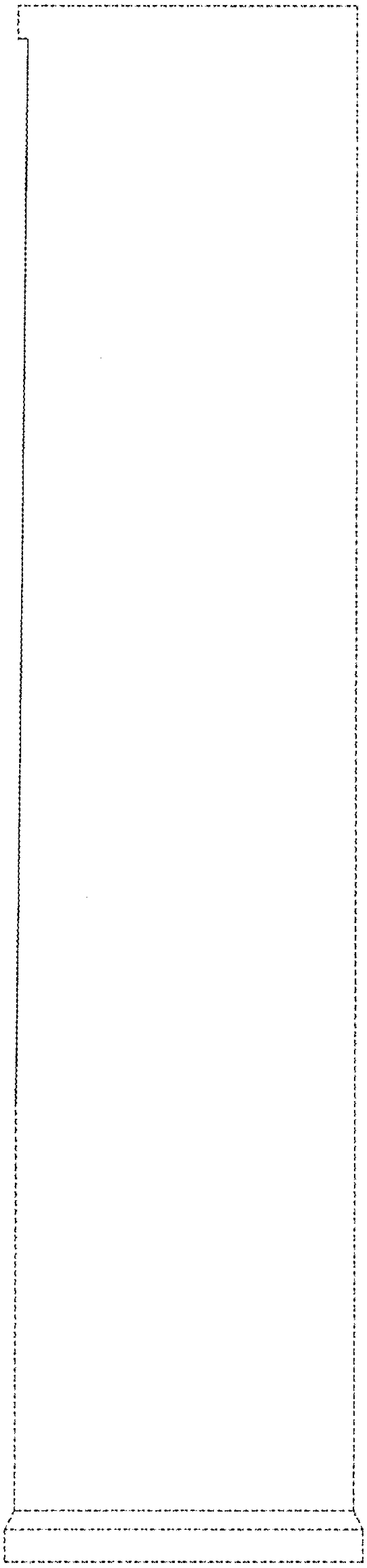

Fig. 5

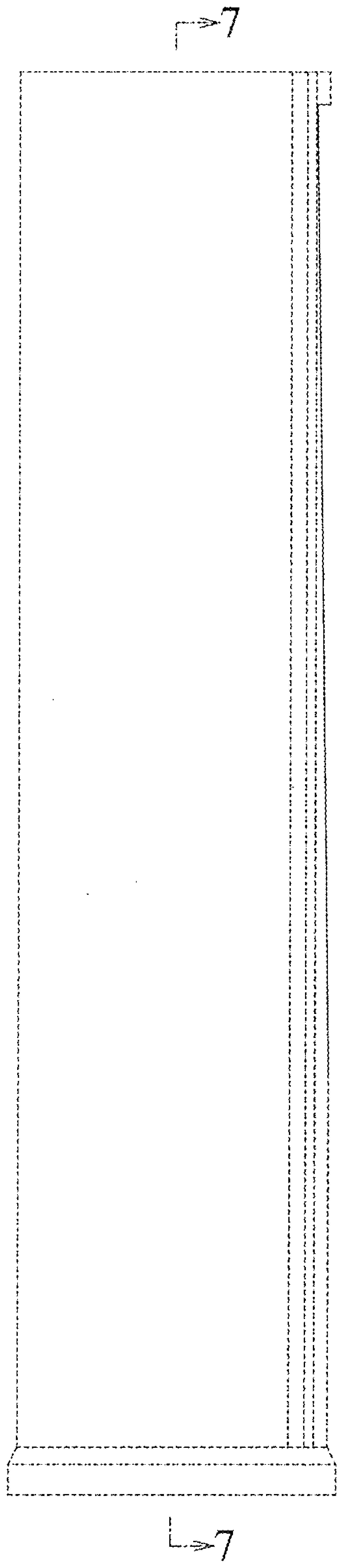

Fig.6

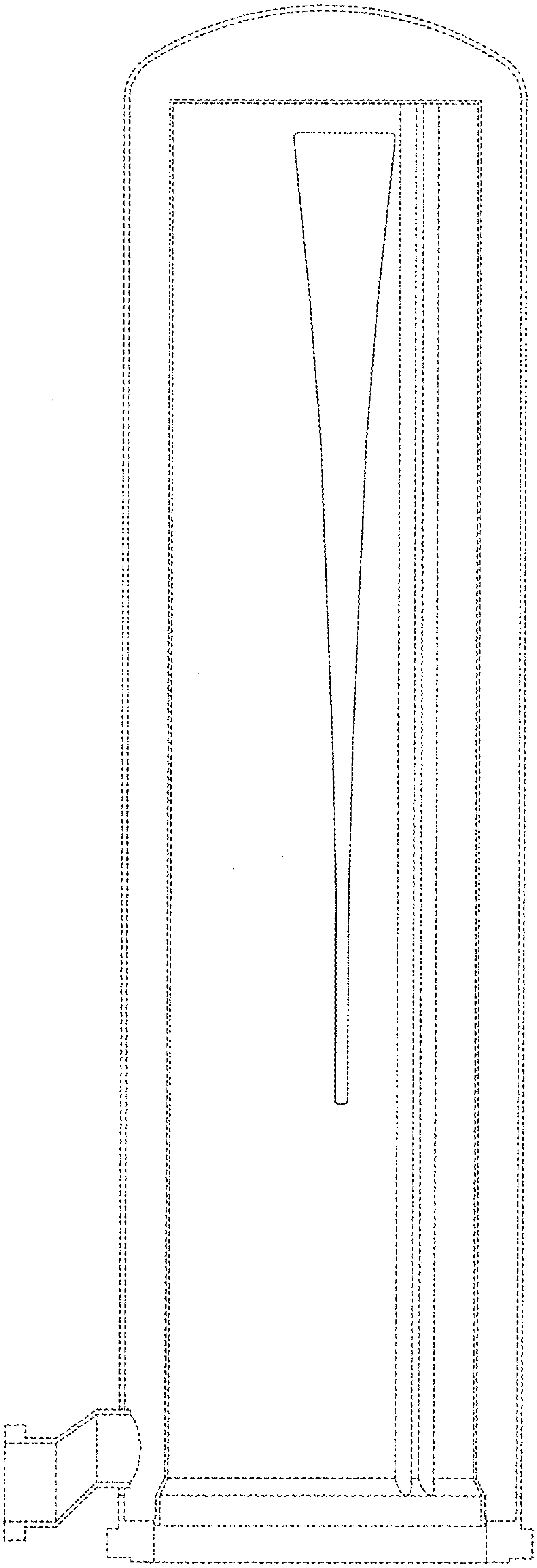

Fig. 7